Korean International Semiconductor Conference & Exhibition on Manufacturing Technology 2025

KISM 2025 BUSAN

Re:Innovation of Semiconductor Manufacturing for AI Ecosystem

Exhibitor Introduction

※ Please write it in English.

Name of Company	KWT SOLUTION Inc.	Company Logo
President	Kwangwon Seo	
Address	Rm505, Amigo Tower, 10, Yatap-ro81beon-gil, Bundang-gu, Seongnam-si, Geyeonggi-do, 13497	
Website	www.kwtsolution.com	
E-mail	software@kwtsolution.com	
Tel.	031-706-2886	
Exhibitor Introduction	KWT Solution Inc. was established with the aim of providing optimal solutions to problems arising in industrial sites as an integrated engineering company. So far, we have contributed to the development of domestic industries through fluid and plasma numerical analysis in various industrial fields such as semiconductors, displays, machinery, aviation, and automobiles. Based on the analysis technology demanded from industrial sites over the years, we aimed to provide a product development network that can be directly applied to the design and production of actual products. We hope that our efforts will be helpful in your work and we will continue to work hard for the development of domestic industries.	
Exhibit Description	At KWT Solution, we are showcasing our internally developed software, K-SPEED Suite and K-PIC, as well as VizGlow from Ram Research (Esgee Technologies) and SimericsMP from Simerics Inc.	
Exhibit Product	K-SPEED Suite : It is a computational analysis program designed to predict three-dimensional semiconductor structures and phenomena such as bowing, necking, etch stop, polymer passivation, and etch rate. K-PIC Suite : It is a software designed for plasma analysis of CCP and ICP equipment within a pressure range from ultra-high vacuum to several Torr, based on the Particle-in-Cell method. VizGlow : It is a fluid-time plasma equipment analysis software. VizGlow uses multiple analysis modules such as electromagnetic fields, flow, and particles to provide various solutions for complex multiphysics problems. It can be used to analyze plasma phenomena in a wide range of pressure areas, from low-pressure areas of tens of mTorr to near atmospheric pressure.	